

IN THE CLAIMS:

Please cancel Claims 1-5 without prejudice.

Please add the following newly drafted Claims 7-12:

- sub 2*
- 1 7. A microelectromechanical system (MEMS) device including a diaphragm
2 comprising a conducting surface, the MEMS device further comprising exactly one layer
3 of C₆₀ fullerene on the conducting surface.
- 1 8. The MEMS device of claim 7, wherein the conducting surface includes gold.
- 1 9. The MEMS device of claim 8, where the C₆₀ fullerene is deposited on the gold
2 surface by sublimation.
- 93*
- 1 10. The MEMS device of claim 8 where the C₆₀ fullerene is deposited on the gold
2 surface by chemisorbtion.
- 1 11. The MEMS device of claim 7 further comprising a single event pipe containing a
2 gas that reacts with carbon byproducts.
- 1 12. A mechanically adjustable electron tunneling tip system comprising:
2 a tunneling tip including a piezoelectric element connected to an end of the
3 tunneling tip;
4 a MEMS device including a conducting surface opposed the tunneling tip; and
5 a single layer of C₆₀ fullerene between the tunneling tip and the MEMS device
6 conducting surface.